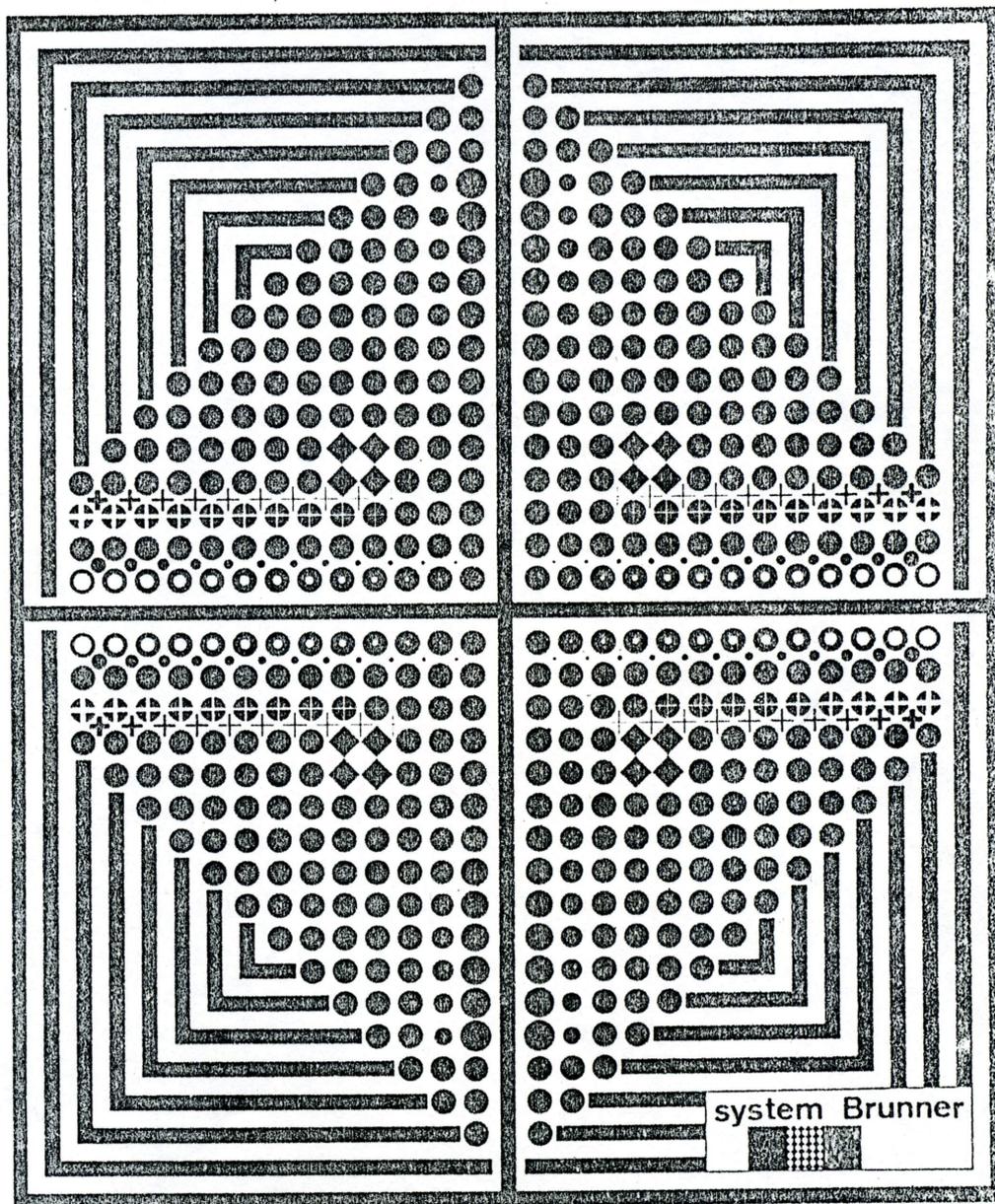


OFFSET QUALITY CONTROL WITH THE BRUNNER SYSTEM



Patent pending

Illustration of the new Brunner System micro-measuring mark enlarged to the size it appears in the corresponding proof projector (26, 5 times). The screen elements are arranged so that a 50% surface coverage for each part of the surface is guaranteed. Hence, this measuring element can both be used for densitometrical and microscopical evaluations. Due to the incorporation of the micro-elements, distortion of screen dots in the contact copy, the offset plate and the production run can be measured with the greatest accuracy. Fine points can be seized up to 0.5% positive and negative. At the same time, the corners of the measuring mark are developed as slurring fields. In addition, the new micro-measuring mark can also be used to check photocomposition and printing of texts.